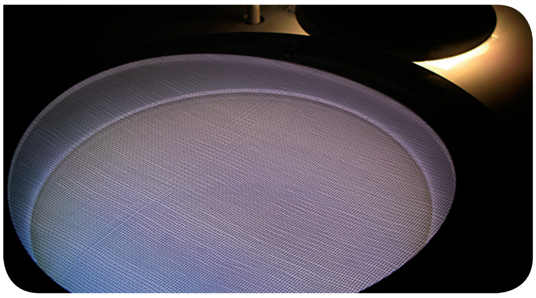
Leybold Optics Lion – RF plasma sources.
Ideal for high-performance coatings.



LEYBOLD OPTICS LION

The LEYBOLD OPTICS LION RF source is based on the electron cyclotron wave resonance principle (ECWR). It is completely integrated in our control systems and dedicated for use in large coating systems like the SYRUSpro 1350 and SYRUSpro 1500. These ion sources combine optimum process operation with ease-of-use and low production cost. Moreover, a single grid (mesh) allows for easy and quick maintenance.

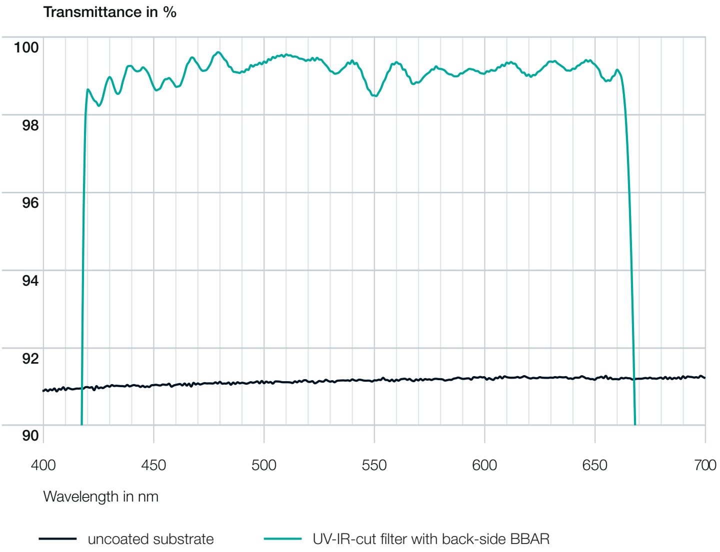
Key benefits:

- Ideal for large chambers
- High power to cover large areas
- High deposition rates
- Layers with very low losses
- Low absorption and scattering
- Easy maintenance
- Low running cost

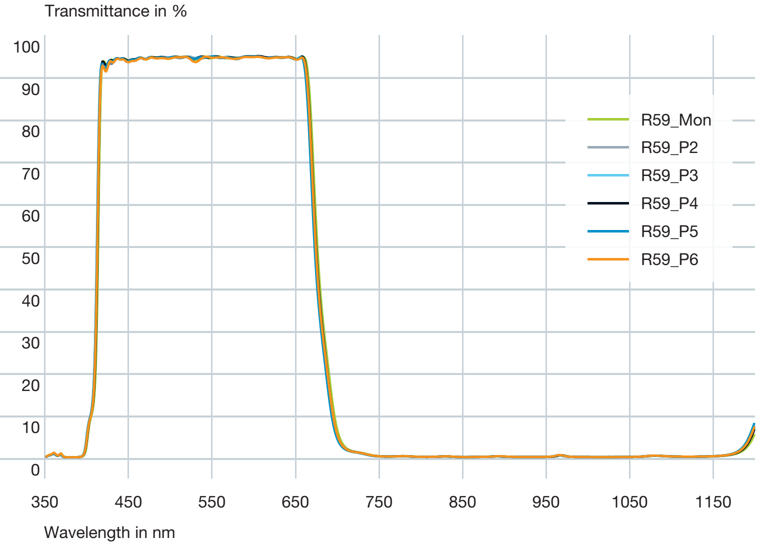
Technical data LION

Free grid-diameter (aperture)	300 mm
RF power	≤ 6.5 kW
Total ion current	≤ 3A
Ion energy	90 – 900 eV
Typical gasses	O2 / Ar / N_2
Matching network	Computerized auto-matching
Ion extraction	Single grid (mesh)

IR-cut-filter



Uniformity



Excellent uniformity over Ø 1400 mm dome (< ± 0.5 %)